

Abstract

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[Purpose]

5 To allow a deposition material to be evenly
supplied to three or more ring hearths.

[Solving means]

10 In a vacuum deposition apparatus which evaporates
a deposition material supplied from a deposition
material supply chamber accommodating a large quantity
of the deposition material lasting long-period
continuous running on a ring hearth in a deposition
chamber to thereby form a film on a substrate
transferred above the ring hearth, three or more of the
ring hearths are arranged side by side in a width
15 direction of the transferred substrate, and the
deposition material is supplied to at least a middle
ring hearth other than ring hearths at both ends by an
electromagnetic vibrating feeder allowed to adjust the
supply quantity of the deposition material.